

# Enhancement of Ionization Efficiency of Acceptors by Their Excited States in Heavily Doped Wide Bandgap Semiconductors

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## 1. Introduction

GaN, SiC and diamond have been attractive wide bandgap semiconductors for devices operating at high powers, high frequencies, and high temperatures. In p-type cases, their acceptor energy level ( $\Delta E_A$ ) are reported to be rather deep. According to the hydrogenic model, a ground state level corresponding to the theoretical  $\Delta E_A$  of a substitutional acceptor in them is expected to be deep because of their dielectric constant lower than Si as well as their hole effective mass heavier than their electron effective mass. For example,  $\Delta E_A$  for SiC is calculated as 146 meV, and the first excited state level ( $\Delta E_2$ ) is estimated to be 36 meV that is close to  $\Delta E_A$  of B in Si. Therefore, the excited states should affect the temperature dependence of the hole concentration  $p(T)$  in p-type wide bandgap semiconductors.

In this article, a distribution function suitable for acceptors in heavily doped p-type SiC and GaN is investigated using  $p(T)$  obtained by Hall-effect measurements. Since the Fermi levels in heavily doped samples are located between the valence band and the acceptor level, which indicates that the Fermi level is close to the excited state levels, there are a lot of holes at the excited states of acceptors. This suggests that a distribution function for acceptors should include the influence of the excited states of acceptors. Therefore, we here consider two distribution functions; (1) the Fermi-Dirac distribution function  $f_{FD}(\Delta E_A)$  not including it and (2) our proposed distribution function  $f(\Delta E_A)$  including it [1-4].

## 2. Distribution function

$f_{FD}(\Delta E_A)$  is described as

$$f_{FD}(\Delta E_A) = \frac{1}{1 + g_A \exp\left(\frac{\Delta E_A - \Delta E_F(T)}{kT}\right)}, \quad (1)$$

where  $\Delta E_F(T)$  is the Fermi level measured from the valence band maximum ( $E_V$ ),  $g_A$  is the acceptor degeneracy factor of 4,  $k$  is the Boltzmann constant, and  $T$  is the absolute temperature.

On the other hand, the distribution function considering the influence of the excited states of acceptors is given by [1-4]

$$f(\Delta E_A) = \frac{1}{1 + g_A(T) \exp\left(\frac{\Delta E_A - \Delta E_F(T)}{kT}\right)}, \quad (2)$$

where

$$g_A(T) = g_A \left[ 1 + \sum_{r=2} g_r \exp\left(\frac{\Delta E_r - \Delta E_A}{kT}\right) \right] \exp\left(-\frac{E_{ex}(T)}{kT}\right) \quad (3)$$

$g_r$  is the  $(r-1)$ th excited state degeneracy factor of  $r^2$ ,  $\Delta E_r$  is the difference in energy between  $E_V$  and the excited state level [ $\Delta E_r = 13.6m_h^*/(m_0\varepsilon_s^2r^2)$  eV],  $E_{ex}(T)$  is an ensemble average energy of the acceptor and excited state levels, given by [1-4]

$$\overline{E_{ex}(T)} = \frac{\sum_{r=2} (\Delta E_A - \Delta E_r) g_r \exp\left(-\frac{\Delta E_A - \Delta E_r}{kT}\right)}{1 + \sum_{r=2} g_r \exp\left(-\frac{\Delta E_A - \Delta E_r}{kT}\right)}, \quad (4)$$

$m_0$  is the free space electron mass,  $m_h^*$  is the hole effective mass, and  $\varepsilon_s$  is the dielectric constant.

## 3. Free carrier concentration spectroscopy

Free carrier concentration spectroscopy (FCCS) is a graphical peak analysis method for determining the acceptor density ( $N_A$ ) and  $\Delta E_A$  from  $p(T)$  using any distribution function. Using an experimental  $p(T)$ , the FCCS signal is defined as [1-4]

$$H(T, E_{ref}) \equiv \frac{p(T)^2}{(kT)^{5/2}} \exp\left(\frac{E_{ref}}{kT}\right), \quad (5)$$

where  $E_{ref}$  is the parameter that can shift the peak temperature within the measurement temperature range. On the other hand, the FCCS signal is theoretically described as [1-4]

$$H(T, E_{ref}) = \frac{N_A}{kT} \exp\left(-\frac{\Delta E_A - E_{ref}}{kT}\right) I(\Delta E_A) - \frac{N_D N_{V0}}{kT} \exp\left(\frac{E_{ref} - \Delta E_F(T)}{kT}\right) \quad (6)$$

where

$$I(\Delta E_A) = N_{V0} \exp\left(\frac{\Delta E_A - \Delta E_F(T)}{kT}\right) F(\Delta E_A), \quad (7)$$

$F(\Delta E_A)$  represents  $f_{FD}(\Delta E_A)$  or  $f(\Delta E_A)$ ,  $N_D$  is

the total donor density,  $N_{V0} = 2(2\pi m_h^* / h^2)^{3/2}$ , and  $h$  is Planck's constant.

Since the FCCS signal has a peak at the temperature corresponding to  $\Delta E_A$ , the values of  $N_A$  and  $\Delta E_A$  can be determined from the peak.

## 4. Experiment

A 400- $\mu\text{m}$ -thick Al-doped 6H-SiC wafer with a resistivity of 1.4  $\Omega\text{cm}$  and a 2- $\mu\text{m}$ -thick Mg-doped GaN epilayer on undoped GaN/sapphire were used. The  $p(T)$  was obtained by Hall-effect measurements in a magnetic field of 1.4 T.

## 5. Results and discussion

Figure 1 shows  $p(T)$  for Al-doped 6H-SiC (circles) and Mg-doped GaN (triangles). Using these  $p(T)$ , the FCCS signals are calculated using Eq. (5).

Figure 2 depicts  $H(T, E_{\text{ref}})$  with  $E_{\text{ref}} = 0.248$  eV for Al-doped 6H-SiC. From the peak of the FCCS signal,  $N_A$ ,  $\Delta E_A$  and  $N_D$  are determined as  $2.5 \times 10^{19} \text{ cm}^{-3}$ , 180 meV and  $7.3 \times 10^{17} \text{ cm}^{-3}$  for  $f_{\text{FD}}(\Delta E_A)$ , and  $3.2 \times 10^{18} \text{ cm}^{-3}$ , 180 meV and  $9.0 \times 10^{16} \text{ cm}^{-3}$  for  $f(\Delta E_A)$ , respectively. The broken and solid lines in Fig. 2 represent the  $H(T, E_{\text{ref}})$  simulations for  $f_{\text{FD}}(\Delta E_A)$  and  $f(\Delta E_A)$  using Eq. (6). The solid line is in better agreement with the circles than the other, indicating that the excited states affect  $p(T)$  obviously. Moreover, since  $N_A - N_D$  determined by capacitance-voltage characteristics was  $4.2 \times 10^{18} \text{ cm}^{-3}$ , the values determined using  $f(\Delta E_A)$  are more reliable than those using  $f_{\text{FD}}(\Delta E_A)$ .

From the peak of the FCCS signal for Mg-doped GaN,  $N_A$ ,  $\Delta E_A$  and  $N_D$  are determined as  $2.1 \times 10^{20} \text{ cm}^{-3}$ , 154 meV and  $2.2 \times 10^{18} \text{ cm}^{-3}$  for  $f_{\text{FD}}(\Delta E_A)$ , and  $8.9 \times 10^{18} \text{ cm}^{-3}$ , 149 meV and  $1.5 \times 10^{17} \text{ cm}^{-3}$  for  $f(\Delta E_A)$ , respectively. Since the Mg concentration determined by secondary ion mass spectroscopy was  $2 \times 10^{19} \text{ cm}^{-3}$ , the values obtained using  $f(\Delta E_A)$  are more reasonable than the other.

Figure 3 shows the  $p(T)$  simulations with  $N_A = 3.2 \times 10^{18} \text{ cm}^{-3}$ ,  $\Delta E_A = 180$  meV and  $N_D = 9.0 \times 10^{16} \text{ cm}^{-3}$  using  $f_{\text{FD}}(\Delta E_A)$  (broken line) and  $f(\Delta E_A)$  (solid line). At high temperatures, the broken line is much lower than the experimental  $p(T)$ . The situation in Mg-doped GaN is the same. These results demonstrate that the excited states enhance the ionization efficiency of acceptors.

## 6. Conclusion

The  $p(T)$  for heavily Al-doped 6H-SiC and Mg-doped GaN were investigated. Since the acceptor levels in them are rather deep, the distribution function including the influence of the excited states of acceptors was required to analyze  $p(T)$ . From the discussion, it is proved that the excited states of acceptors enhance the ionization efficiency of acceptors.

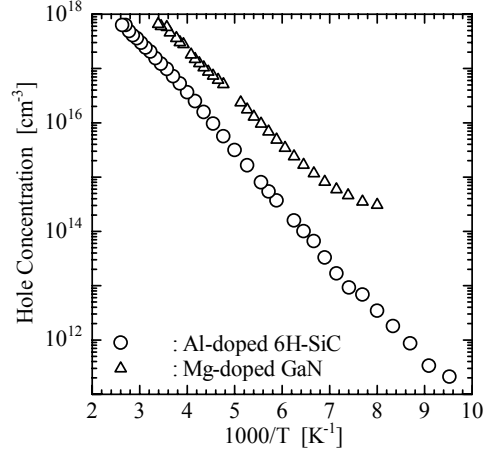


Figure 1. Experimental  $p(T)$ .

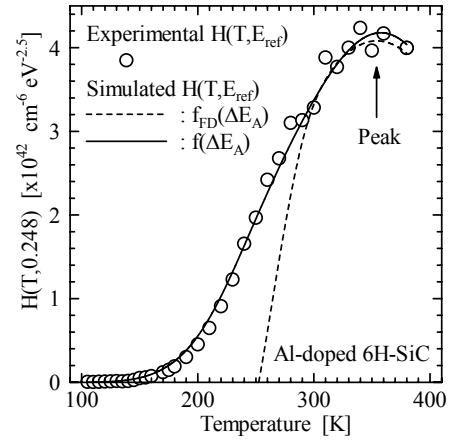


Figure 2. FCCS signal.

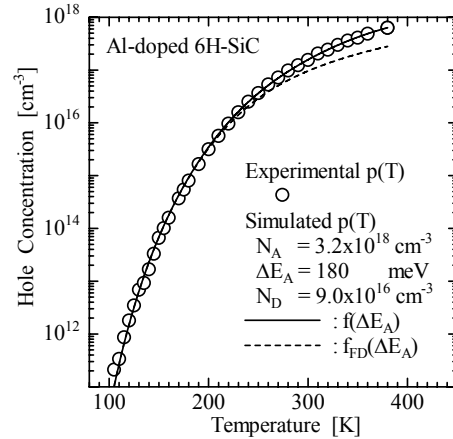


Figure 3.  $p(T)$  simulations for  $f_{\text{FD}}(\Delta E_A)$  and  $f(\Delta E_A)$  with the same values.

## References

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